

II. CLAIM AMENDMENTS

1. (Currently Amended) A system for accessing data remotely from a network, comprising:

a first network ~~interface card~~ permitting data transfer between a local network comprising at least one semiconductor processing tool and semiconductor processing tool monitoring equipment and an intermediate network comprising an equipment diagnostic monitoring system configured to monitor and analyze the at least one semiconductor processing tool;

a second network separate from the first network ~~interface card~~ permitting data transfer between the intermediate network and a remote network comprising remote control equipment configured to allow a user remote access to the at least one semiconductor processing tool; and

a module located within the intermediate network, through which all data transferring between the local network and the remote network must pass, the module being configured to provide indirect remote access to at least one semiconductor processing tool located in the local network and to prevent an unauthorized interception of communications between the local network and the remote network related to the at least one semiconductor processing tool;

wherein the local network may either receive and act upon or not receive and not act upon information transmitted by the remote network depending on a set of predetermined criteria

applied by the intermediate network.

2. (Original) The system of claim 1, wherein the data transfer between each of the networks occurs via the Internet Protocol (IP), and wherein each network has its own unique IP address.

3. (Original) The system of claim 2, wherein the module hides the IP addresses of the remote network and the local network from each other.

4. (Currently Amended) The system of claim 1, wherein the module exchanges data with an equipment diagnostic monitor system located within the intermediate network, and wherein the equipment diagnostic monitor system has the function of monitoring tests performed on the at least one semiconductor processing tool residing within the local network.

5. (Currently Amended) The system of claim 4, wherein the equipment diagnostic monitor system collects and analyzes data from tests performed on the at least one semiconductor processing tool.

6. (Currently Amended) A system for accessing a local network from a remote network through an intermediate network, comprising:

a first network ~~interface card~~ permitting data transfer between the local network comprising at least one semiconductor processing tool and semiconductor processing tool monitoring equipment and the intermediate network;

a second network separate from the first network interface

~~card~~-permitting data transfer between the remote network and the intermediate network;

a module located within the intermediate network, through which all data transferring between the local network and the remote network must pass, wherein the data is selectively passed between the local network and the remote network depending on a set of predetermined criteria applied by the intermediate network and, the module being configured to provide indirect remote access to at least one semiconductor processing tool located in the local network and to prevent an unauthorized interception of communications between the local network and the remote network related to the at least one semiconductor processing tool; and

an equipment diagnostic monitor system located within the intermediate network, wherein the equipment diagnostic monitor system monitors tests performed on at the least one item semiconductor processing tool residing within the local network.

7. (Original) The system of claim 6, wherein the data transfer between each of the networks occurs via the Internet Protocol (IP).

8. (Original) The system of claim 7, wherein the module hides the IP addresses of the local network and the remote network from each other.

9. (Currently Amended) The system of claim 6, wherein the equipment diagnostic monitor system collects and analyzes data from the tests performed on the at least one semiconductor processing tool~~item~~.

10. (Currently Amended) The system of claim 6, wherein a user on the remote network may request that tests be performed on the at least one semiconductor processing tool~~item~~, and may upload data to the remote network, from the tests performed on the at least one semiconductor processing tool~~item~~.

11. (Currently Amended) A data system, comprising:

a first network interface device enabling data transfer between a local network and an intermediate network;

a second network interface device enabling data transfer between a remote network and the intermediate network, the intermediate network is configured to provide indirect remote access to at least one semiconductor processing tool located in the local network and to prevent an unauthorized interception of communications between the local network and the remote network related to the at least one semiconductor processing tool; and

an equipment diagnostic monitor system located within the intermediate network, wherein the equipment diagnostic monitor system monitors tests performed on at least one semiconductor processing tool ~~item~~ in the local network;

wherein data is selectively transferred between the local network and the remote network depending on a set of predetermined criteria applied by the intermediate network.

12. (Previously Presented) The system of claim 11, further comprising a security module located within the intermediate network, through which all data transferring between the local

network and the remote network must pass.

13. (Original) The system of claim 12, wherein data transfer between each of the networks occurs via the Internet Protocol (IP).

14. (Original) The system of claim 13, wherein the module hides the IP addresses of the local network and the remote network from each other.

15. (Currently Amended) The system of claim 11, wherein the equipment diagnostic monitor system collects and analyzes data from tests performed on the at least one semiconductor processing tool~~item~~.

16. (Currently Amended) The system of claim 11, wherein a user on the remote network may request that tests be performed on the at least one semiconductor processing tool, and upload data from previous tests performed on the at least one semiconductor processing tool~~item~~, and said request may be optionally executed or ignored based on a set of predetermined criteria.

17. (Currently Amended) The system of claim 11, wherein a user on the remote network may send a suggestion regarding the operation of the at least one semiconductor processing tool ~~item~~ being monitored to an entity managing the semiconductor processing tool ~~item~~ on the local network.

18. (Currently Amended) The system of claim 11, wherein the equipment diagnostic monitor system sends an alert to a predetermined entity when the analysis of tool data indicates

that the at least one semiconductor processing tool item is operating outside of a predetermined performance range.

19. (Previously Presented) The system of claim 1 further comprising a remote control proxy server in the intermediate network that is between the local network and the remote network that prevents direct IP routing to a device in the local network that is being accessed by the remote network.

20. (Previously Presented) The system of claim 1 further comprising a semiconductor tool coupled to the local network, a user being able to access the semiconductor tool via the remote network.

21. (Previously Presented) The system of claim 20, wherein the intermediate network further comprises an equipment diagnostic monitor system that monitors and analyzes the semiconductor tool.

22. (Previously Presented) The system of claim 21, wherein the equipment diagnostic monitor system controls tests performed by software within the semiconductor tool, saves data from the tests and sends out alerts to a remote user via the remote network when the semiconductor tool is operating outside a predetermined performance range.

23. (Previously Presented) The system of claim 21, wherein the equipment monitor system effects access to the semiconductor tool by a remote user.